

FORM PTO 1449 (modified)  U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE  LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)  Date Submitted to PTO: February 2, 2001				ATTY DOCKET NO. <b>1960.30 DIV. I</b>		APPLICATION NO. NYA <b>09/773674</b>		PTO 09/773674 02/02/01
				APPLICANT <b>TIMOTHY M. RICHARDSONI</b>		FILING DATE <b>February 2, 2001</b>	GROUP <b>2877</b>	
U.S. PATENT DOCUMENTS								
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLAS S	FILING DATE IF APPROPRIATE	
<i>W.B.</i>		4,056,376	10/77	Dabervo	350	10		/
<i>W.B.</i>		5,622,796	4/97	Canestrari, et al.	430	22		
<i>W.B.</i>		4,616,241	10/86	Biefeld, et al.	357	16		
<i>W.B.</i>		4,947,223	8/90	Biefeld, et al.	357	30		
<i>W.B.</i>		5,027,178	6/91	Svilans	357	30		
<i>W.B.</i>		5,608,519	3/97	Gourley, et al.	356	318		
FOREIGN PATENT DOCUMENTS								
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLAS S	TRANSLATION YES/NO/ OR ABSTRACT	
<i>W.B.</i>		0,214,1601	5/90	Europe	G01B	7/34	Abstract	
<i>W.B.</i>		2,702,277	9/94	France	G01M	11/00	—	
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)								
EXAMINER <i>W.B.</i>				DATE CONSIDERED <i>27 Oct 2001</i>				

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Sheet 1 of 2

FORM PTO 1449 (modified)		ATTY DOCKET NO. 1960.30 DIV. I	APPLICATION NO. NYA 09/77367A PTO
U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		APPLICANT TIMOTHY M. RICHARDSONI	
LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)		FILED DATE February 2, 2001	GROUP 2877
Date Submitted to PTO: February 2, 2001			
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)			
W.D.		Electro-Optical Systems Design; OTF Quantitative Image Analysis; David Smith, Dec. 1979.	
W.D.		Cambridge University Press; Nanofabrication And Biosystems, H. Hoch, L.W. Jelinski, and H.G. Craighead.	
W.D.		Development In Semiconductor Microlithography; Testing The Mann Type 4800DSW™ Wafer Stepper™, W. Schneider, vol. 174, pp. 6-14 (1979)	
W.D.		JENOPTIK, Laser Optik Systeme	
W.D.		"Contrast Transfer In Confocal Microscopy" by R. Oldenbourg, et al.	
EXAMINER	DATE CONSIDERED		23 Oct 2004

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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